

Claims

1. Device for drying disc-shaped substrates comprising
 an elongated body (1),
 which tapers upwards to form a wedge having an angle α between two upper
 5 surfaces and the upper edge (2)
 wherein the upper edge (2) is suitable for a disc-shaped substrate to be supported
 on, characterized in that
 an upper surface (3) comprises a groove (4) having an increasing groove depth
 with increasing distance from the upper edge (2).
- 10 2. Device according to claim 1, characterized in that
 the wedge opening angle α is larger than 30° and smaller than 90° , preferably
 larger than 50° and smaller than 70° .
3. Device according to claim 1 or claim 2, characterized in that
 the material used for the device comprises ceramic filled polyetheretherketone
 15 (CFM PEEK).
4. Device according to claim 1 to claim 3, characterized in that
 the curvature radius is not less than 0.1 mm and not more than 1mm.
5. Device according to claim 1 to claim 4, characterized in that
 the maximum groove depth is not less than 1 mm and not more than 5mm.
- 20 6. Device according to claim 1 to claim 5, characterized in that
 an upper surface (3) comprises not less than 3 grooves (4).
7. Device according to claim 1 to claim 6, characterized in that
 the groove (4) has a triangular shape.
8. Device according to claim 7, characterized in that
 25 the opening angle of the triangular shape of a groove is not less than 80° and not
 more than 100° .

9. Method of drying a disc-shaped substrate using a device according to any of claims 1 to 8.